# TEST OF SILICON SENSORS FOR LUXE

ADA

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#### SENSORS

- 90 CALICE sensors received from Hamamatsu.
  320 um thickness, 16x16 pads (5.5x5.5 mm2)
- Labeled and stored in dry cabinet with membrane boxes

Parameter	Rating	Unit
Device type	P+ PIXEL on N substrate	
Chip size	89700 ± 40 x 89700 ± 40	μm
Active area	88480 x 88480	μm
Chip thickness	320±15	μm
Number of PIXELs	256(16 x 16)	ch
PIXEL pitch	5530 x 5530	μm
PIXEL GAP	10	μm

Parameter	Symbol	Condition	Min	Тур	Max	Unit
substrate resistitance			3		-	kΩ∙cm
Full depletion voltage	Vfd		15		120	V
leakage current(for inner PIXEL*2)	Id	VR=200V			25	nA
leakage current(for outer PIXEL*2)	Id2	VR=200V			100	nA
Number of NG PIXEL					10	ch





### PROBE STATION

- The manual probe station has been donated by DESY Zeuthen 15 years ago. It has been automatized by adding a switch card connected to a probe card (sensor design dependent) developed at CERN
- Originally designed for lumical sensors





### PROBE STATION

- CALICE probe card arrived
- Probe station updated to accept the new probe card. Cooling, gas, pump cleaned and working
- Software updated for the new probe card (configuration files)





CALICE probe card

#### SENSOR DATA

- Data from the probe station are saved on the local computer
- Then transferred to the CERN cloud (CERNBOX accessible by the collaboration)
- Analyzed by python soft to produce plots and alarm if needed
- For each sensor, one excel file produced with 256 sheets containing plots (CV,IV) for each pad. The excel file is uploaded to the CERN cloud.

#### **Sensors and infrastructure :**

- All sensors arrived and stored in good conditions
- Probe station has been modified and ready to test
- Data are saved and shared with the collaboration



#### DATA TAKING

- 1<sup>st</sup> step : contact test to be sure all the pads are touching the probe pins. Takes few minutes
- 2<sup>nd</sup> step IV test.
- 3<sup>rd</sup> step CV test.
- We are adding the following steps :
  - Rotation of the sensors (90 degrees)
  - Contact test
  - IV and CV for the missing pins







### IV MEASUREMENT

Checked the influence of different parameters: delay between measurements, delay between voltage change,...

System tuned

Up to now, 25 x 256 pads measured with current plateau



#### CV MEASUREMENT

- 100 CV measurement on the same pad to check the repeatability •
- Measurement of the system every 10 CV measurements (to be • subtracted)





149.1

149.2

149.3

149.0

148.9

### DEPLETION VOLTAGE

• It is possible to extract the depletion voltage from the CV measurement; the capacitance can be modelized by:

• 
$$C_g = A \frac{\varepsilon_{Si}\varepsilon_0}{w} = \begin{cases} A \sqrt{\frac{\varepsilon_{Si}\varepsilon_0 eN_d}{2V}} \text{ for } V < V_d, A: pad area Nd : number of donor, V bias voltage} \\ A \frac{\varepsilon_{Si}\varepsilon_0}{w_m} \text{ for } V > Vd, w_m \max. depletion width \end{cases}$$

• So if we take the log of Cg, we should obtain two lines. The intersection of these lines is giving the depletion voltage



## DEPLETION VOLTAGE

• Define the depletion voltage per pad :







### DEPLETION VOLTAGE

• Fit per sensor -> mean, sigma



This corresponds to the expected values



### DONOR DENSITY

• It is possible to determine the donor density using the formula :

$$\frac{1}{C^2} = \frac{2}{\varepsilon e N_d A^2} V$$

Where N<sub>d</sub> is the donor density and A is the pad area





### DONOR DENSITY





This is compatible with the values found with lumical sensor



### CONCLUSION

- We have a working setup to characterize silicon sensors, including analysis and storage : we can test two sensors a day (without the rotation)
- All the pads of the tested sensors have a plateau in the IV plot
- Using the CV measurement, it is possible to extract the depletion voltage and the donor density. These extracted values are compatible with expectations

